

NanoTera Workshop on Next-Generation MOSFET Compact Models  
EPFL, December 15-16, 2011

# Analog performance of advanced CMOS and EKV3 model

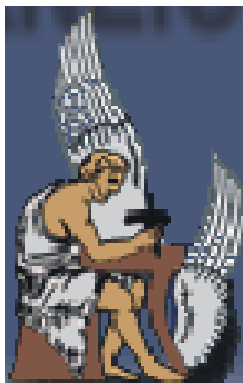
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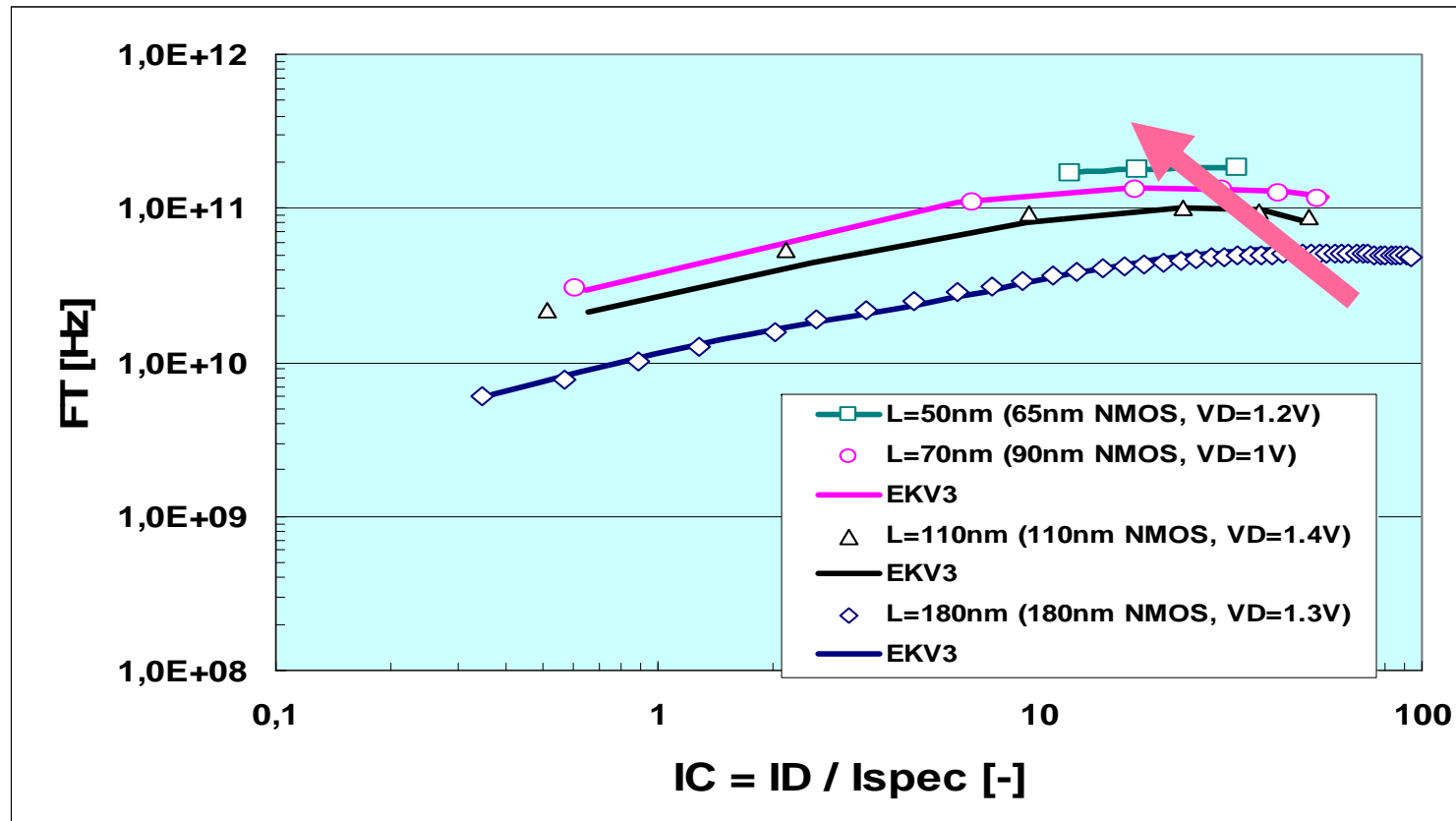


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# Outline

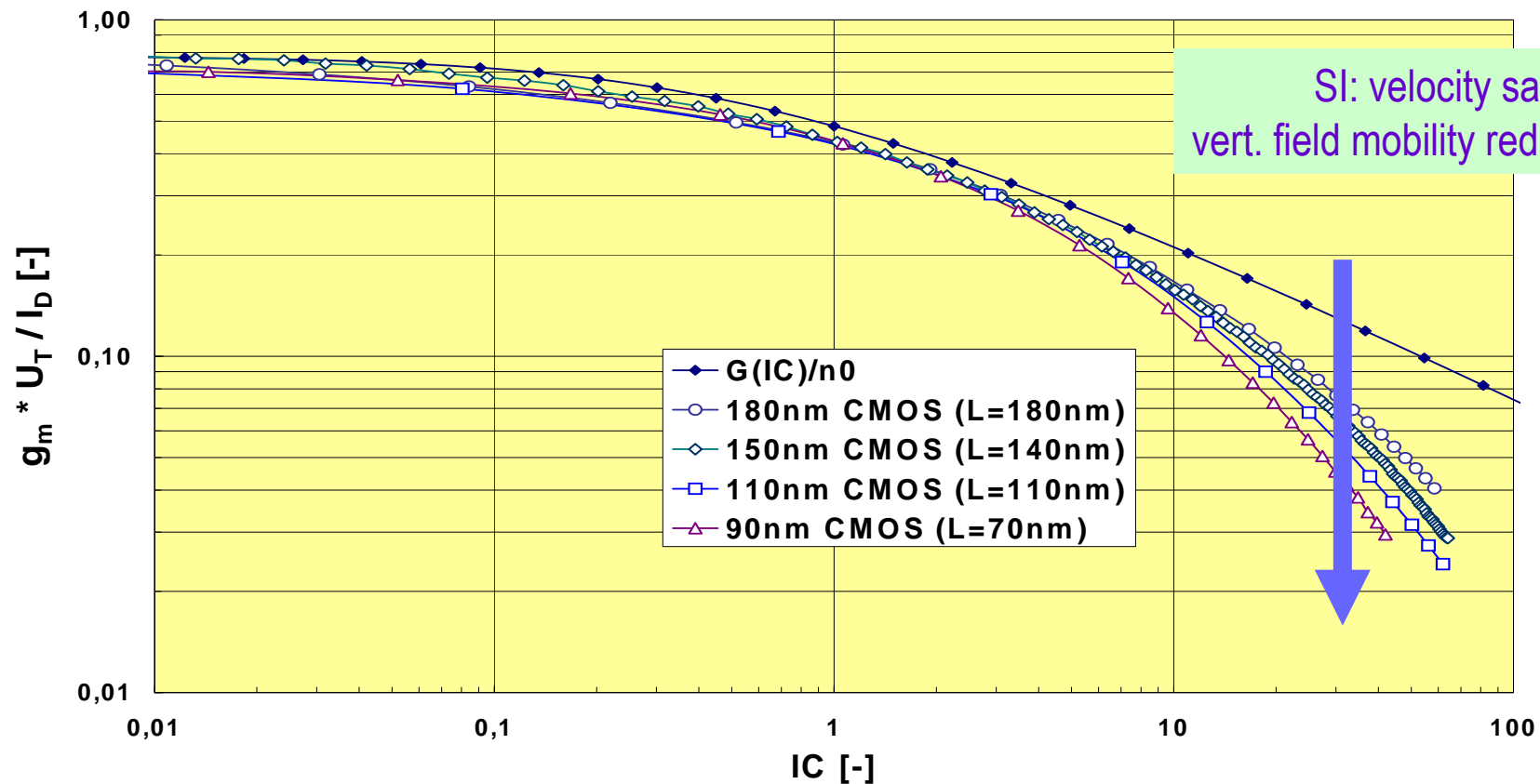
- Motivation – the need for moderate inversion design
- Evolution of CMOS device performance – from planar bulk to double-gate and FinFET
- EKV3 charge-based compact model
- EKV3 high-frequency model
- Conclusions

# Scaling of $F_T$ for 180nm $\rightarrow$ 65nm CMOS



- NMOS transistors, high  $V_D$  bias (variable)
- $F_T$  reaches 187, 134, 101, 52 GHz, respectively
- A plateau (max.  $F_T$ ) is reached
  - ✓ slightly above Moderate Inversion (MI,  $0.1 < IC < 10$ )
  - ✓  $IC \approx 20 \dots 50$ , depends on  $V_D$

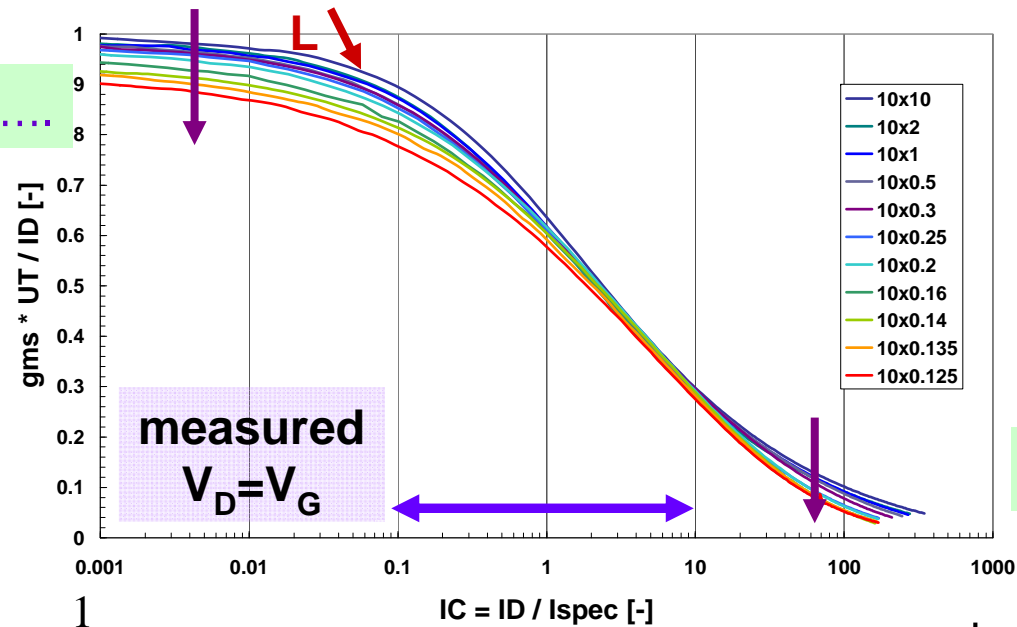
# Scaling of normalized transconductance



- Weak Inversion (WI,  $IC < 0.1$ ): highest transconductance per given current
- Strong Inversion (SI,  $IC > 10$ ): stronger degradation due to higher fields in more advanced technology

# Normalized transconductance

WI: (DIBL, CS) STI....



SI: VS, CLM....

$$\frac{g_{ms} \cdot U_T}{I_D} = G(IC) = \frac{1}{\frac{1}{2} + \sqrt{\frac{1}{4} + IC}}$$

Moderate Inversion

L = 10 um → 125nm

Inversion Coefficient:

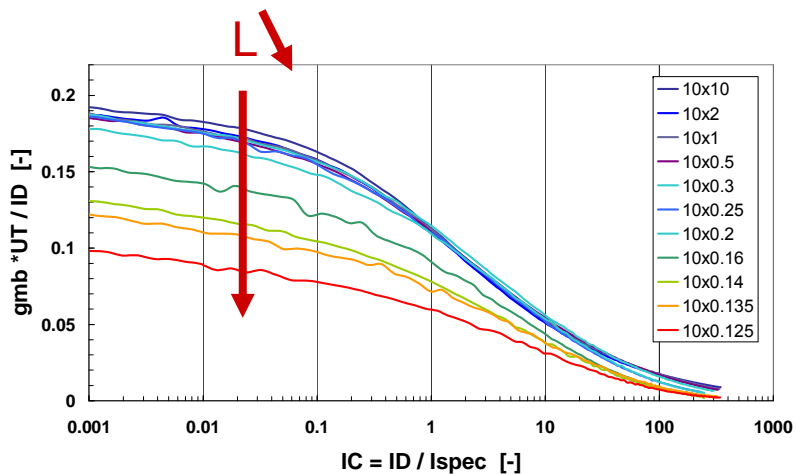
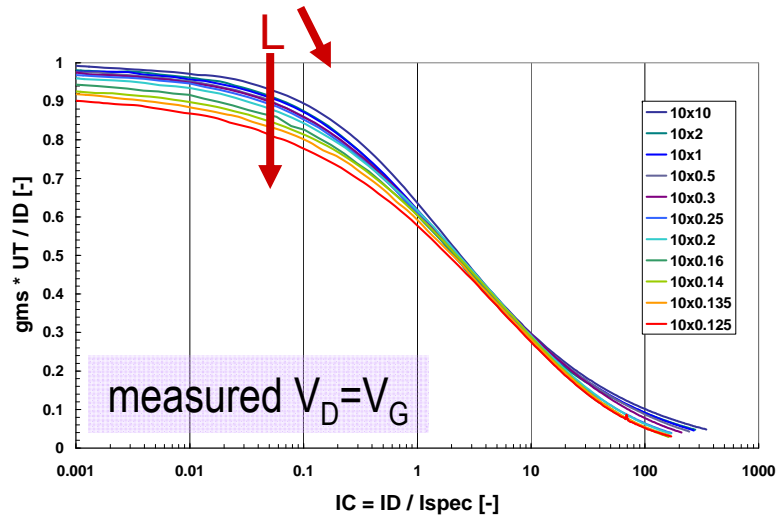
$$IC = \frac{I_D}{I_{SPEC}}$$

Specific Current:

$$I_{Spec} = 2nU_T^2 \mu C'_{ox} \frac{W}{L}$$

- Normalization factor for drain current:  $I_{spec}$
- Normalized  $g_m$  and  $g_{ds}$  vs. IC and L
- Anomalous scaling of output conductance in WI

# $g_{ms}/I_D, g_{mb}/I_D$ vs. $IC, L$



Moderate Inversion

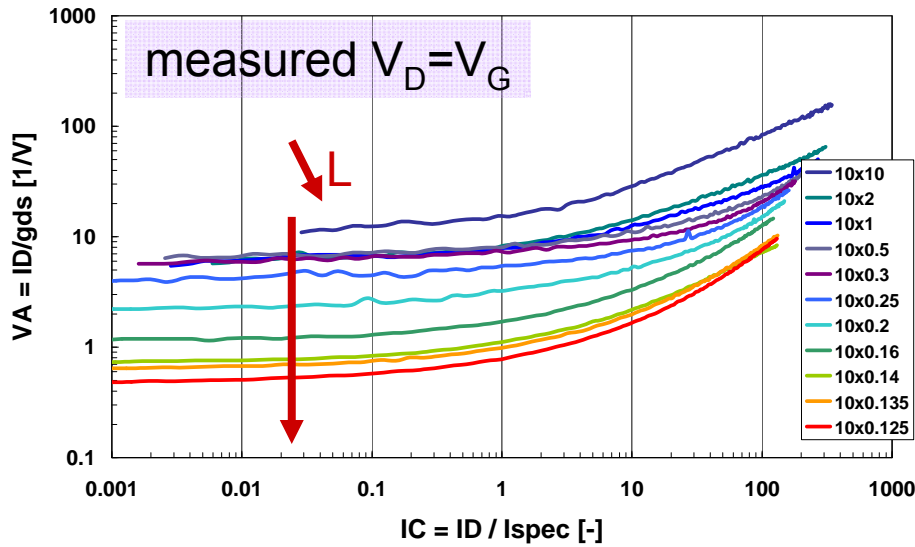
$$\frac{g_{ms} \cdot U_T}{I_D} = G(IC) = \frac{1}{\frac{1}{2} + \sqrt{\frac{1}{4} + IC}}$$

$$\frac{g_m \cdot U_T}{I_D} = \frac{1}{n} \cdot G(IC)$$

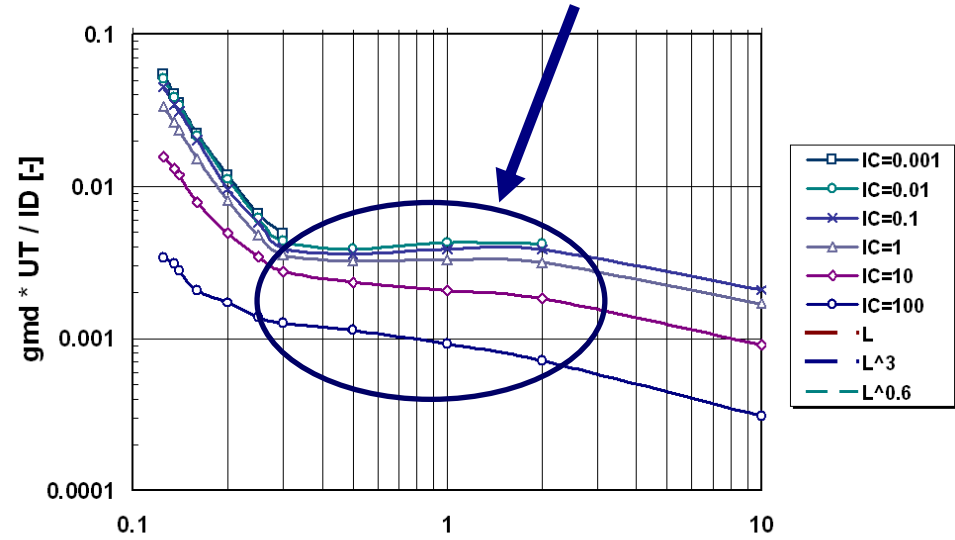
$$\frac{g_{mb} \cdot U_T}{I_D} = \frac{n-1}{n} \cdot G(IC)$$

- EKV model offers convenient estimation of large- and small-signal quantities for ideal charge-based MOSFET – not available from other modelling approaches

# Early voltage vs. IC, L



Moderate Inversion

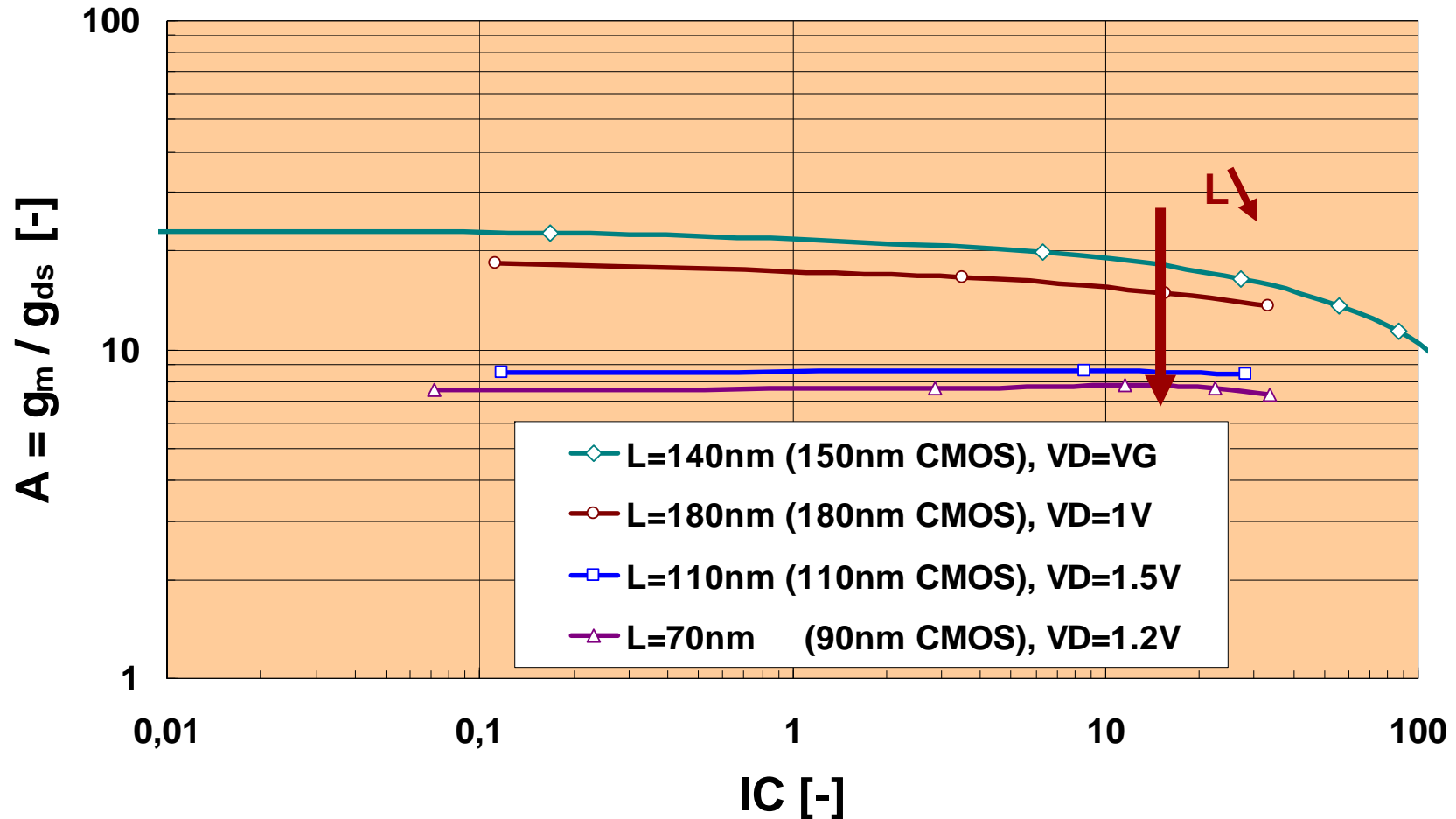


$$\frac{U_T}{V_A} = \frac{g_{ds} \cdot U_T}{I_D} \approx \left( \frac{\partial V_{TO}}{\partial V_D} \right) \cdot \frac{1}{n} \cdot G(IC)$$

- Early Voltage  $V_A$  scaling is dominated by DIBL effect ( $\delta V_{TO} / \delta V_D$ )
  - ✓  $V_A$  scaling related to transconductance function  $G(IC)$
- In strong inversion, velocity saturation & CLM dominate
- Anomalous scaling of output conductance in WI

DIBL effect dominates gds in WI-MI

# Scaling of DC gain – planar bulk CMOS



- DC gain is strongly degraded (@minimum length!) for scaled CMOS → problem for analog/RF design!

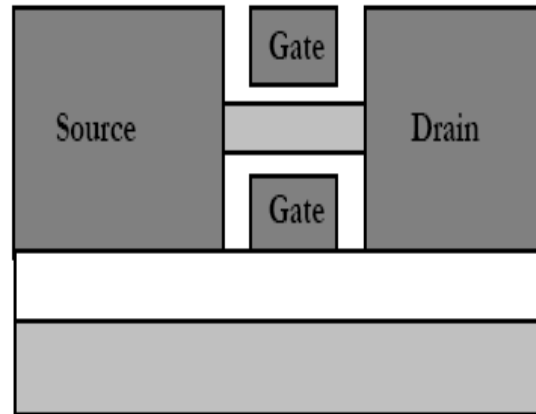


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# Outline

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- Evolution of CMOS device performance – from planar bulk to double-gate and FinFET
- EKV3 charge-based compact model
- EKV3 high-frequency model
- Conclusions

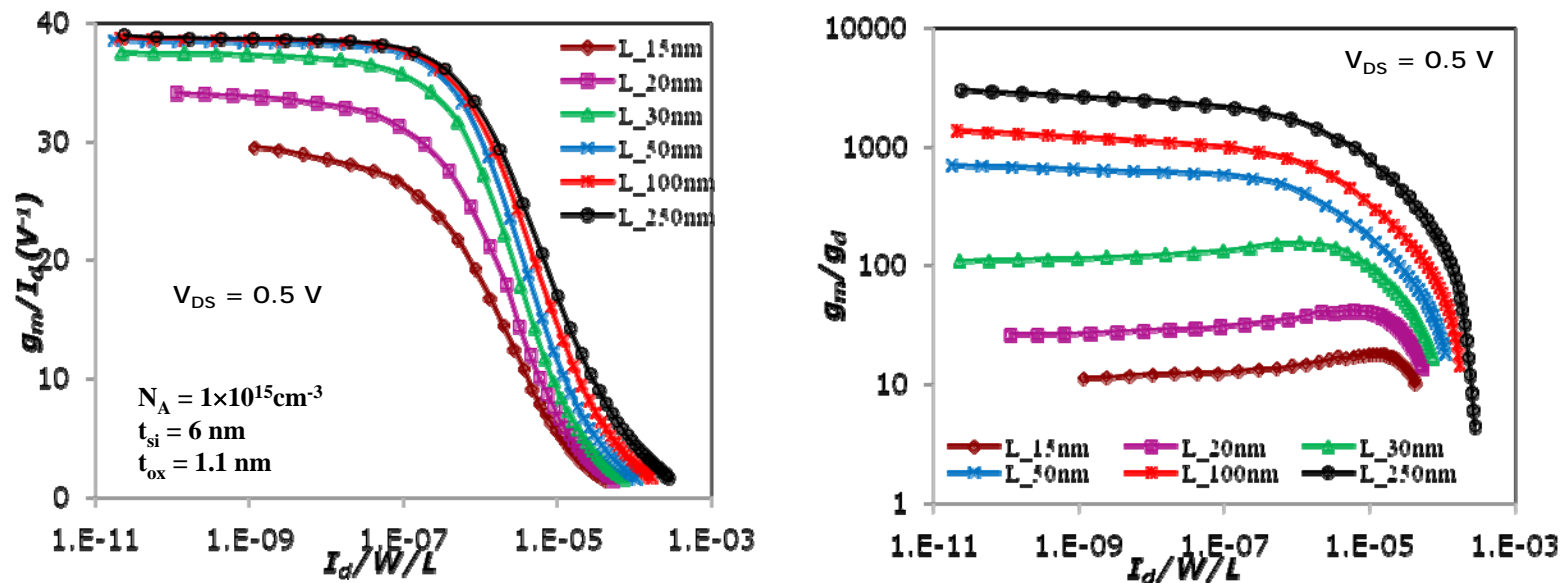
# Double gate MOSFETs



- DG MOSFET is (one of !?!) the most promising device, because it has less geometry effects such as corner and narrow width effects
- The two gates are easy to be biased separately as they are formed in different process steps
  - symmetric or asymmetric operation possible
- Effective control of short channel effects
- Higher current drive capability and transconductance
- Ideal weak inversion slope

# Double gate FET – transconductance and gain scaling

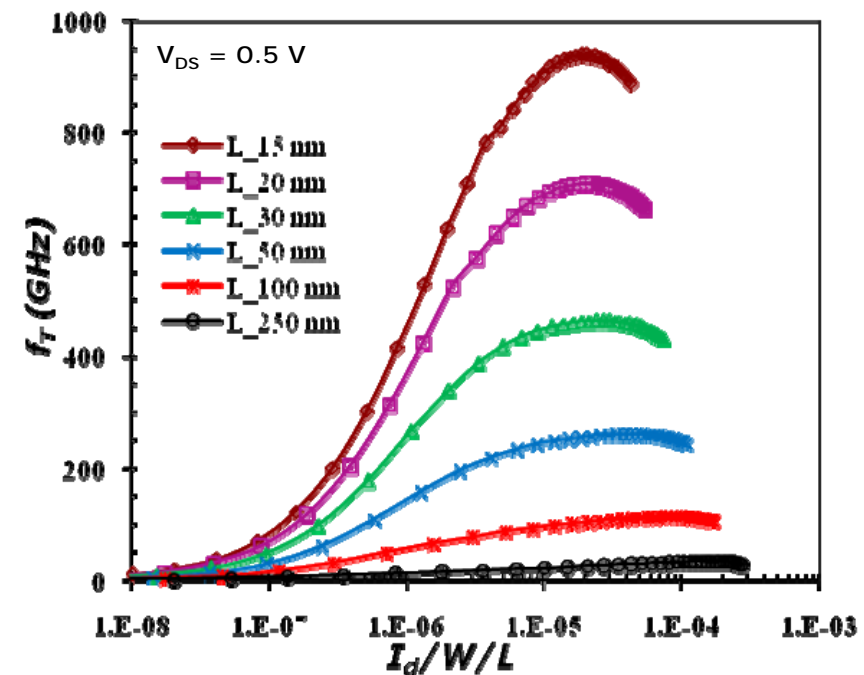
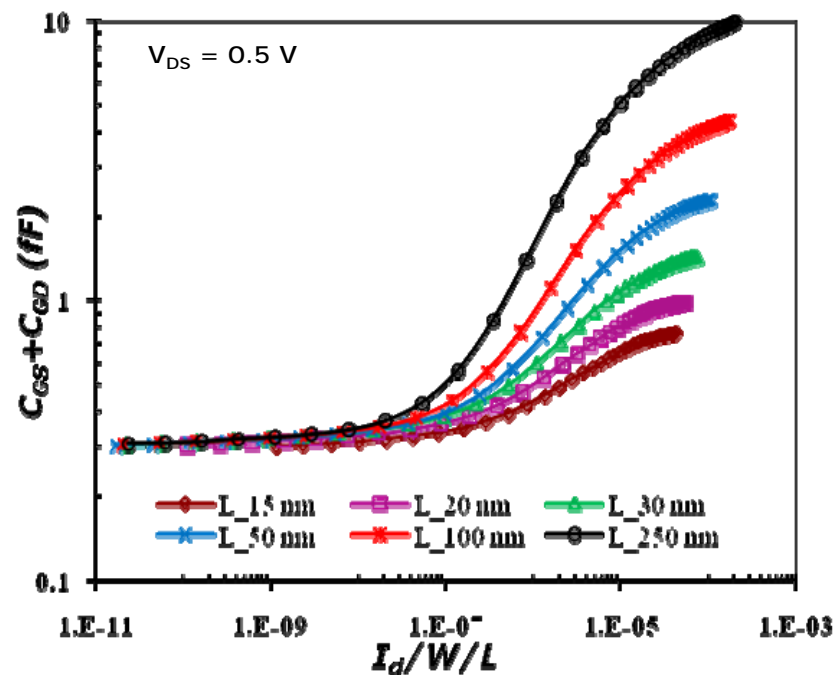
Transconductance efficiency ( $g_m/I_D$ ) and intrinsic gain ( $g_m/g_{ds}$ )



- For gate lengths below 50 nm, important decrease in device efficiency and voltage gain → drain/gate engineered DG MOSFETs required
- TCAD simulation

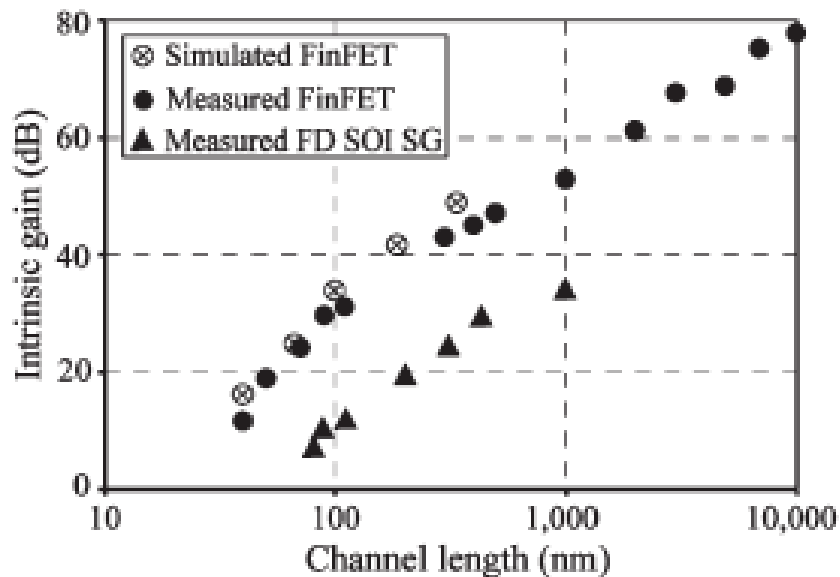
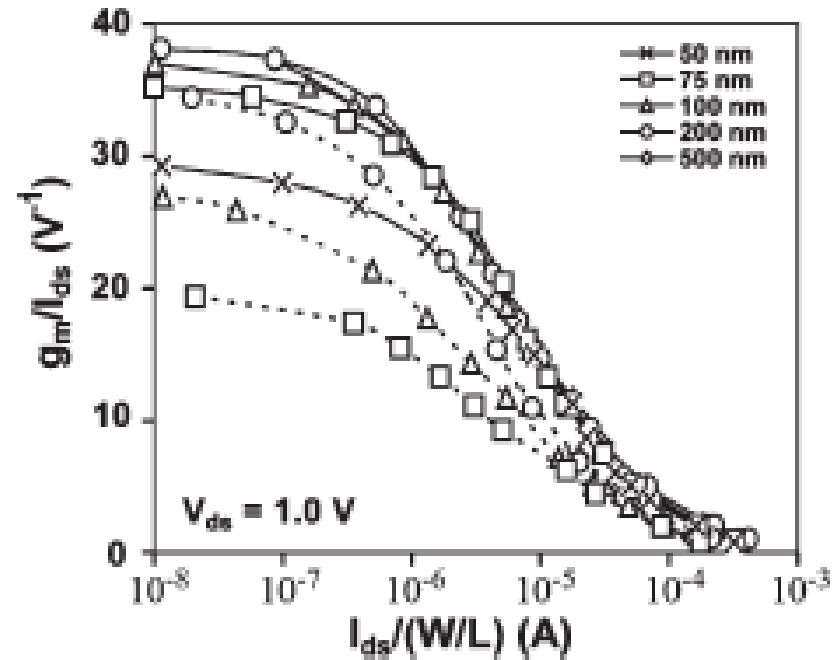
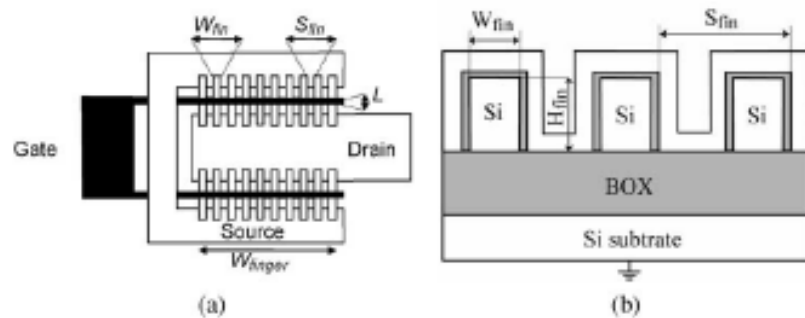
# Double gate FET – capacitance and $F_T$ scaling

Capacitance  $C_{GS}+C_{GD}$  and cut-off frequency  $F_T$



- Extremely high speed of intrinsic devices
- Parasitics need to be considered

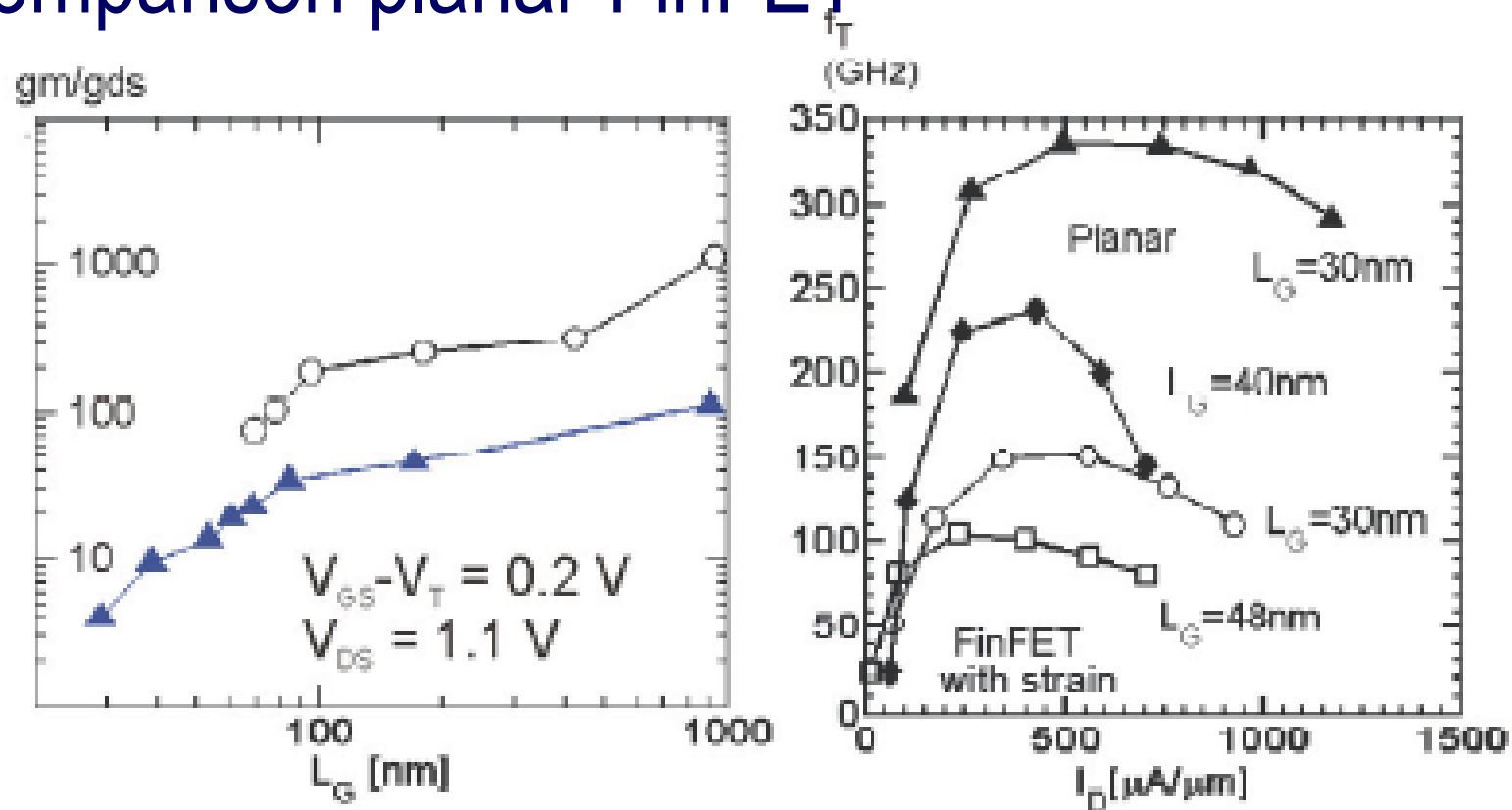
# FinFET transconductance & gain



Raskin e.a., TED(53), 2006

- FinFET: short-channel effects on  $g_m/I_D$

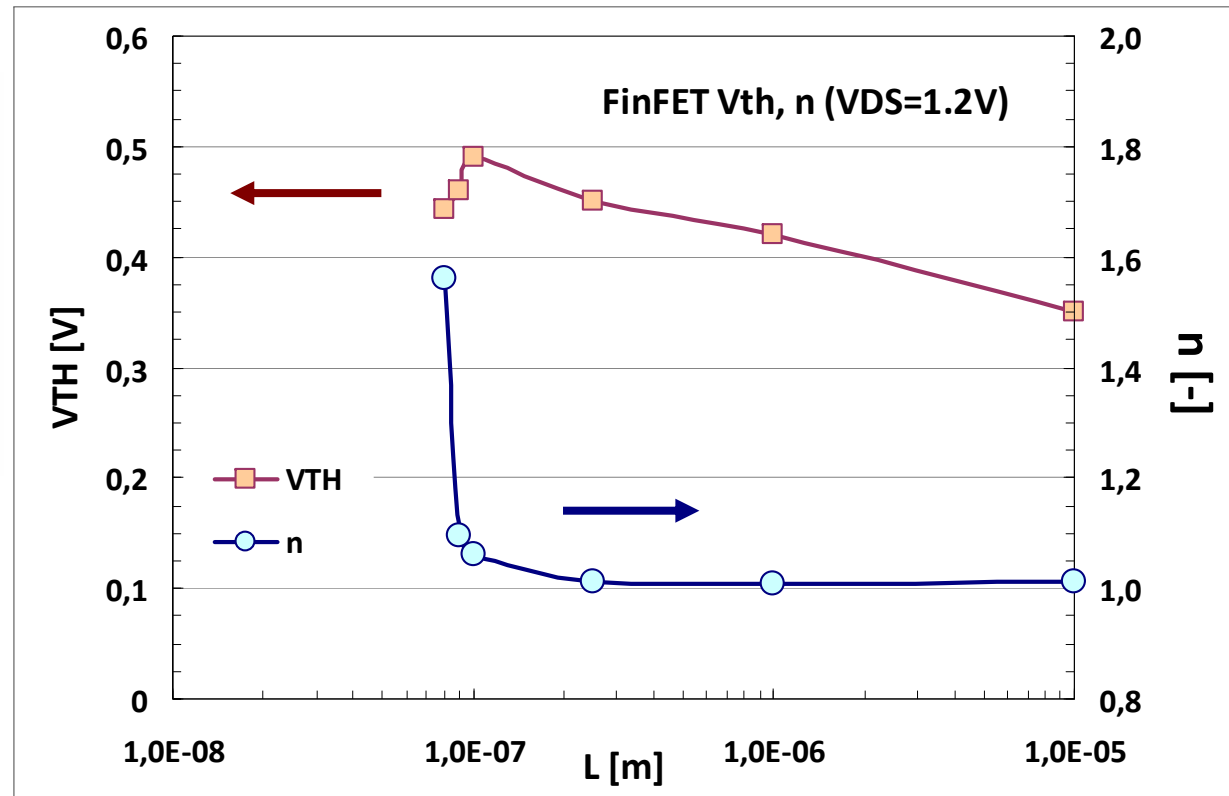
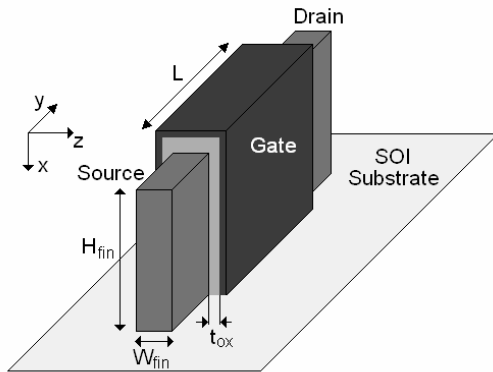
# Comparison planar-FinFET



Wambacq e.a., ISSCC 2008

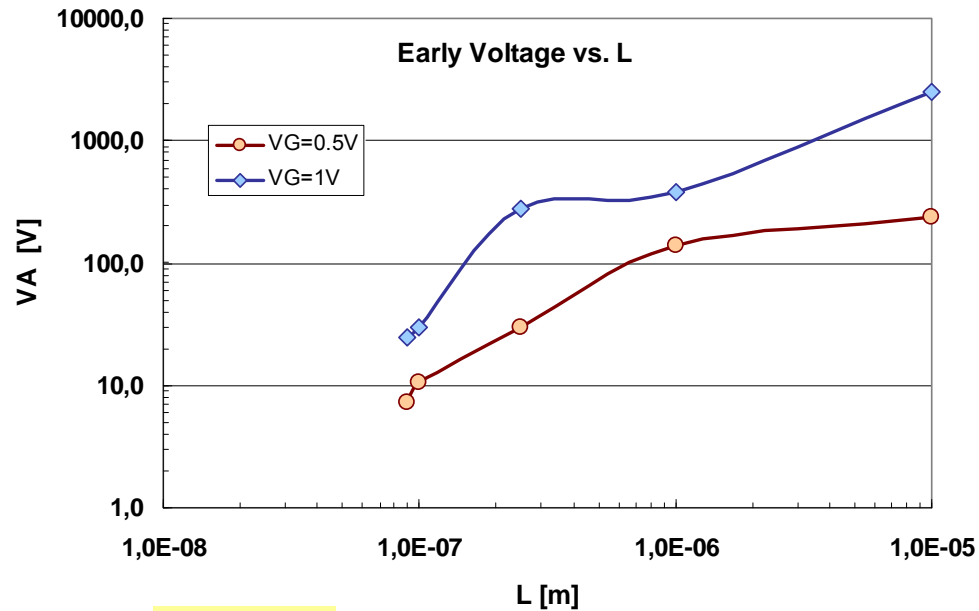
- Better  $g_m/g_{ds}$  in FinFETs compared to planar
- Higher speed in planar bulk CMOS (strained silicon)
- Higher parasitic capacitances – series resistance in FinFETs

# FinFET $V_T$ & $n$ scaling



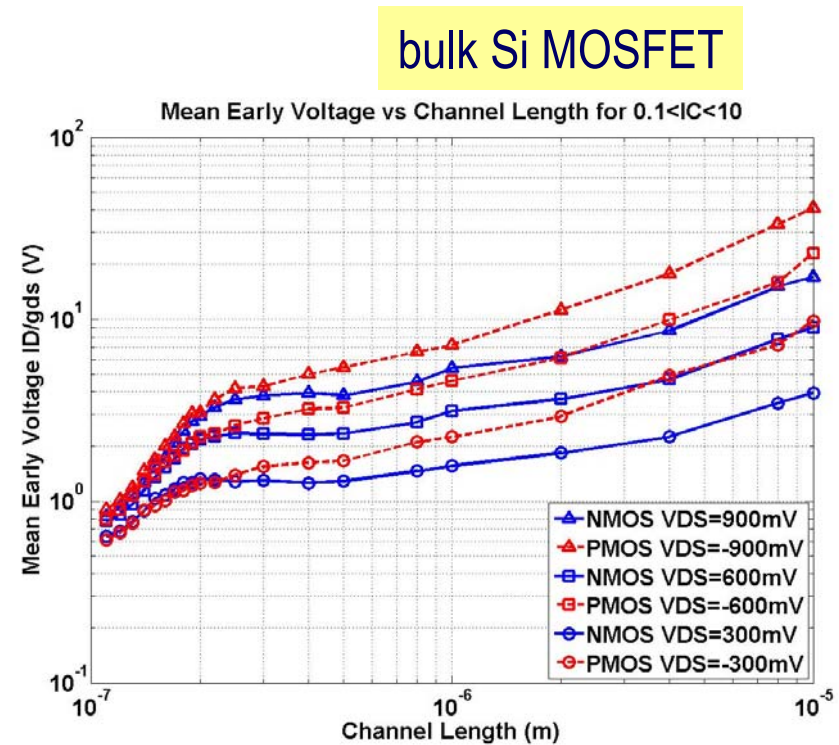
- 80nm, n-FinFETs, measured characteristics.
- Scaling versus channel length – RSCE appears
- Show severe subthreshold slope degradation @  $L=80\text{nm}$

# FinFET Early voltage scaling



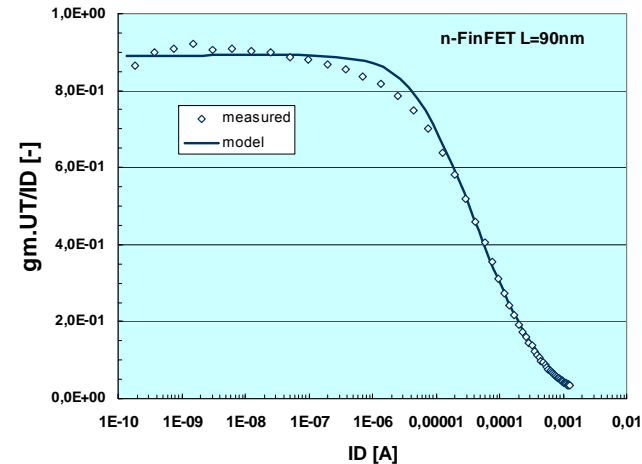
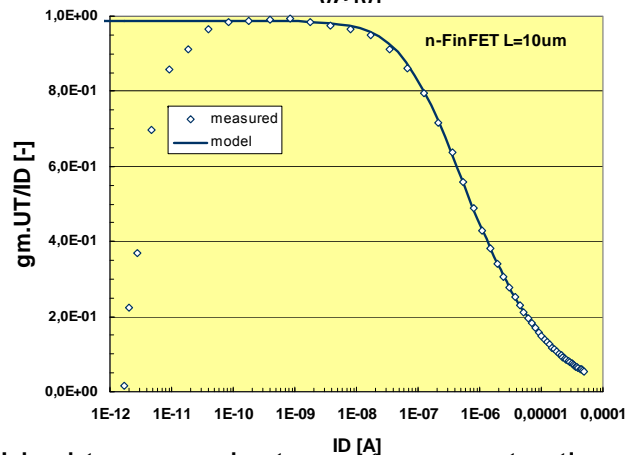
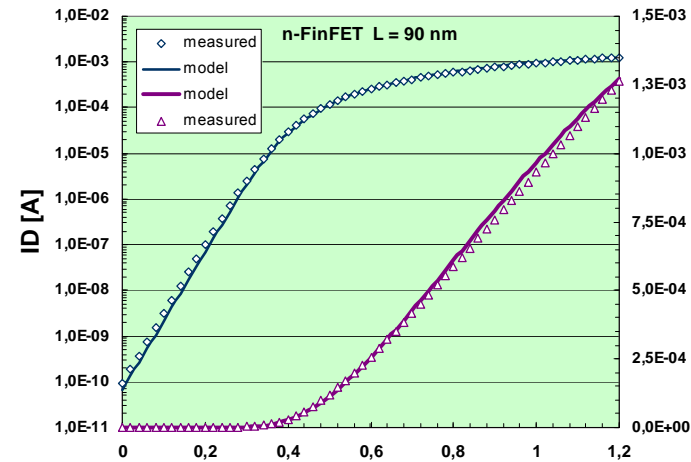
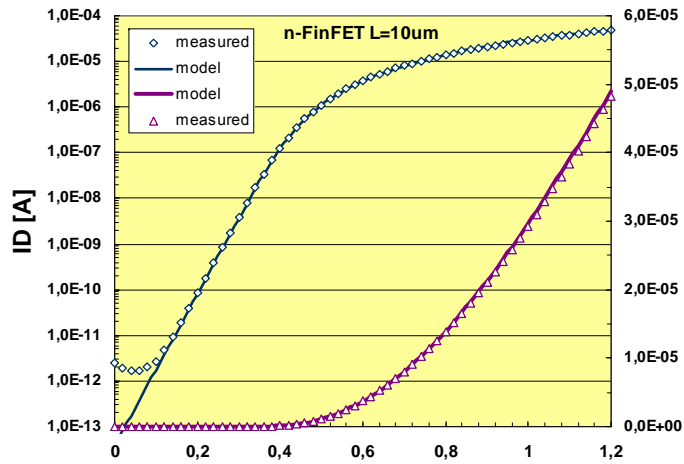
FinFET

- 80nm n-FinFETs
- $V_A$  scaling versus channel length
- FinFET Early voltage is very high  $V_{A,FinFET} \geq 10V_{A,planar\ bulk}$  @same L
- entails high intrinsic gain vs. planar



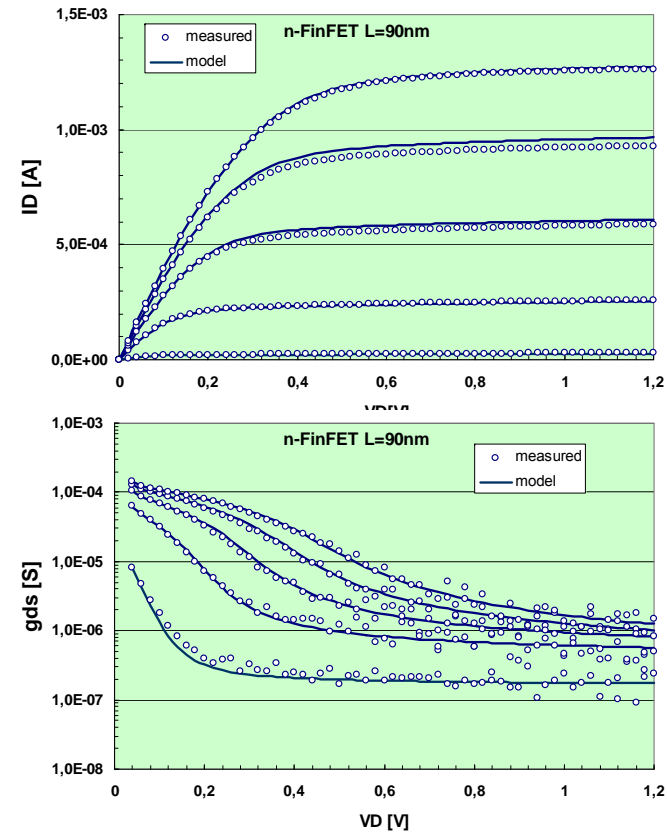
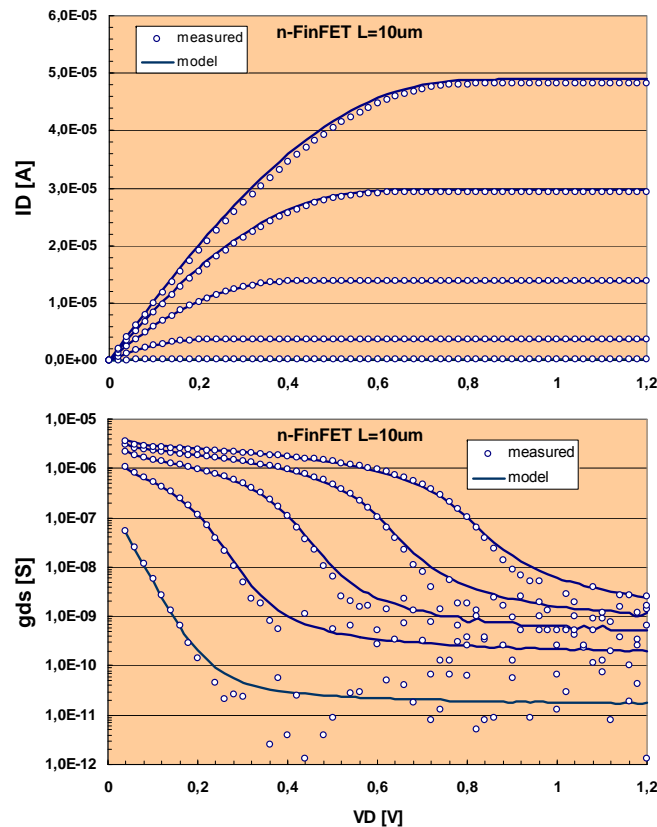


# FinFET IV modelling with EKV3



- Ideal transconductance to current ratio
- “planar-like” (very low substrate doping)
- Short channel weak inversion slope remains good (L=90nm)
- similar observations as in planar bulk Si MOSFETs – moderate inversion degradation of gm/ID

# FinFET IV modelling with EKV3



- Short-channel output characteristics
- Velocity saturation effects, CLM, DIBL, ... needed
  - ✓ many similarities with bulk Si MOSFETs

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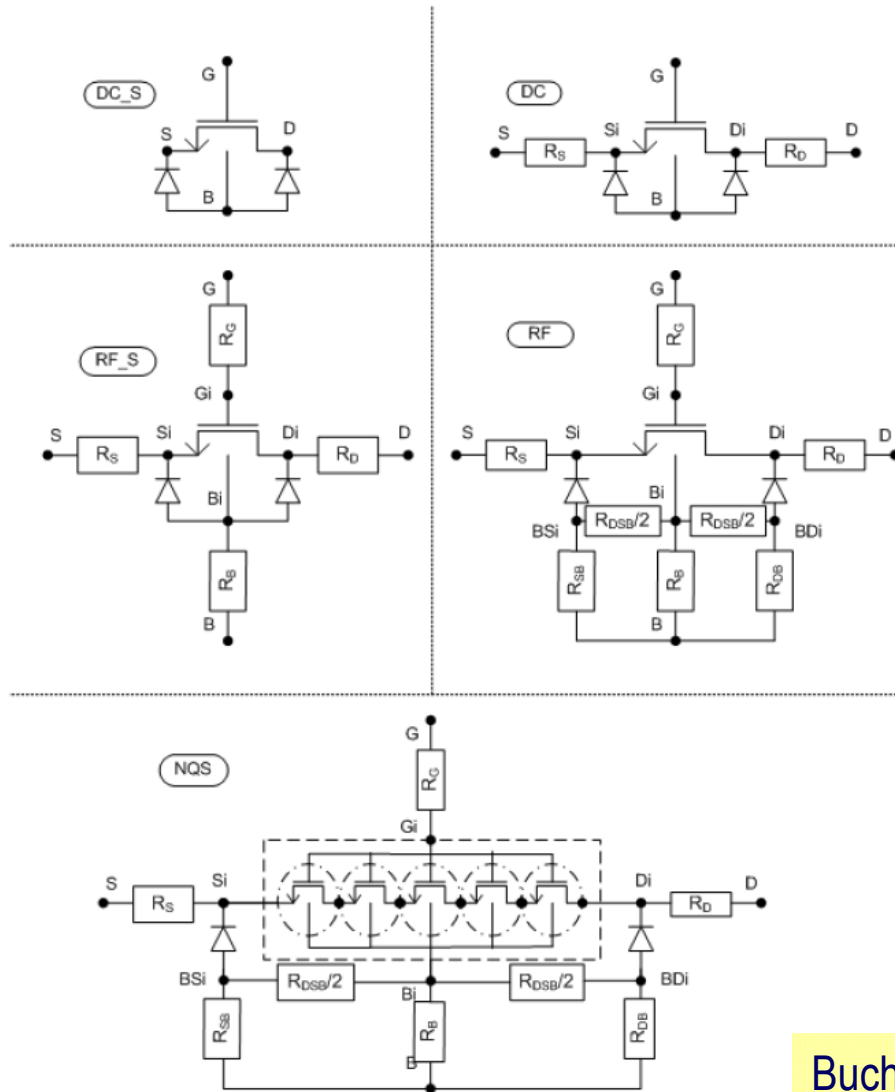
# Outline

- Motivation – the need for moderate inversion design
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- **EKV3 charge-based compact model**
- EKV3 high-frequency model
- Conclusions

# EKV3 model overview

- Due to CMOS scaling, ICs operate more and more in moderate and weak inversion
- Design methods and models are required
  - ‘classical’ methods don’t cover moderate inversion
- EKV3 is a Compact MOS Transistor Model dedicated to Analog/RF IC design
  - ✓ Developed as a successor of EKV2.6
  - ✓ Full charge-based modelling approach – close to physics and design
  - ✓ Special attention to analog/RF IC design requirements
  - ✓ Covers essential effects down to 45nm CMOS
  - ✓ Scaling over Technology – Width – Length – T – Bias
  - ✓ EKV3 available for implementation to CAD vendors.

# Configurations of EKV3

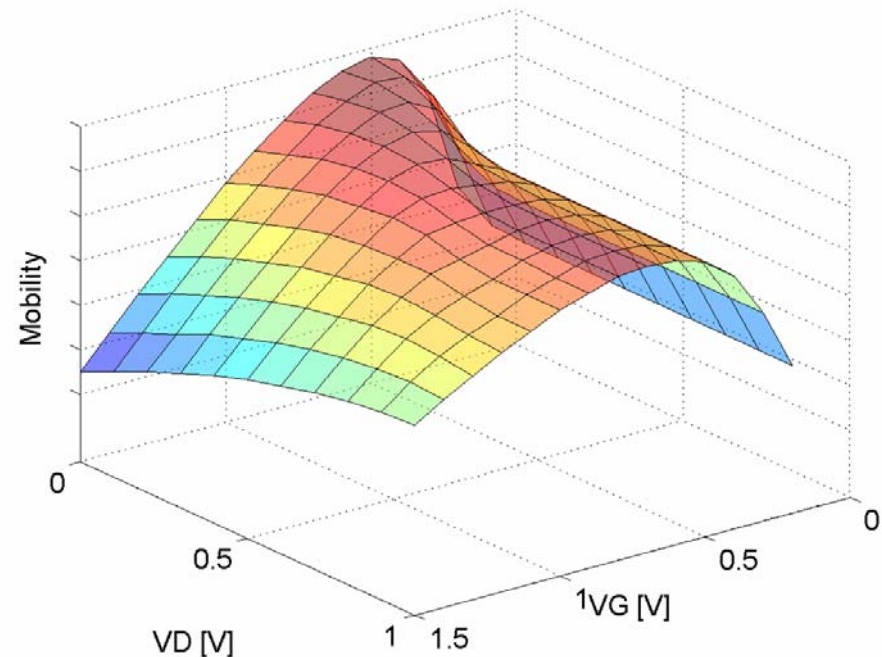


- Simple model – only internal accounting for (S,D) series resistance
- Simple model with external series resistance
- Simple RF model with gate and substrate resistance
- Full RF model with substrate resistivity network
- Full RF & NQS (channel segmentation) model.

Bucher e.a., SSE(52), 2008

# EKV3 – charge based model & extensions

- Basis of charge model development is surface potential equation & inversion charge linearization
  - ✓ Same parameters as surface potential model
  - ✓ Preserves the essence of a surface potential model.
- Extensions for CV:
  - ✓ Vertical non-uniform doping
  - ✓ Polydepletion
  - ✓ Quantum effects
- Extensions of IV:
  - ✓ Charge-based vertical field mobility
  - ✓ Charge-based velocity saturation
  - ✓ Charge-based CLM
  - ✓ Gate tunnelling



# EKV3 model scaling effects

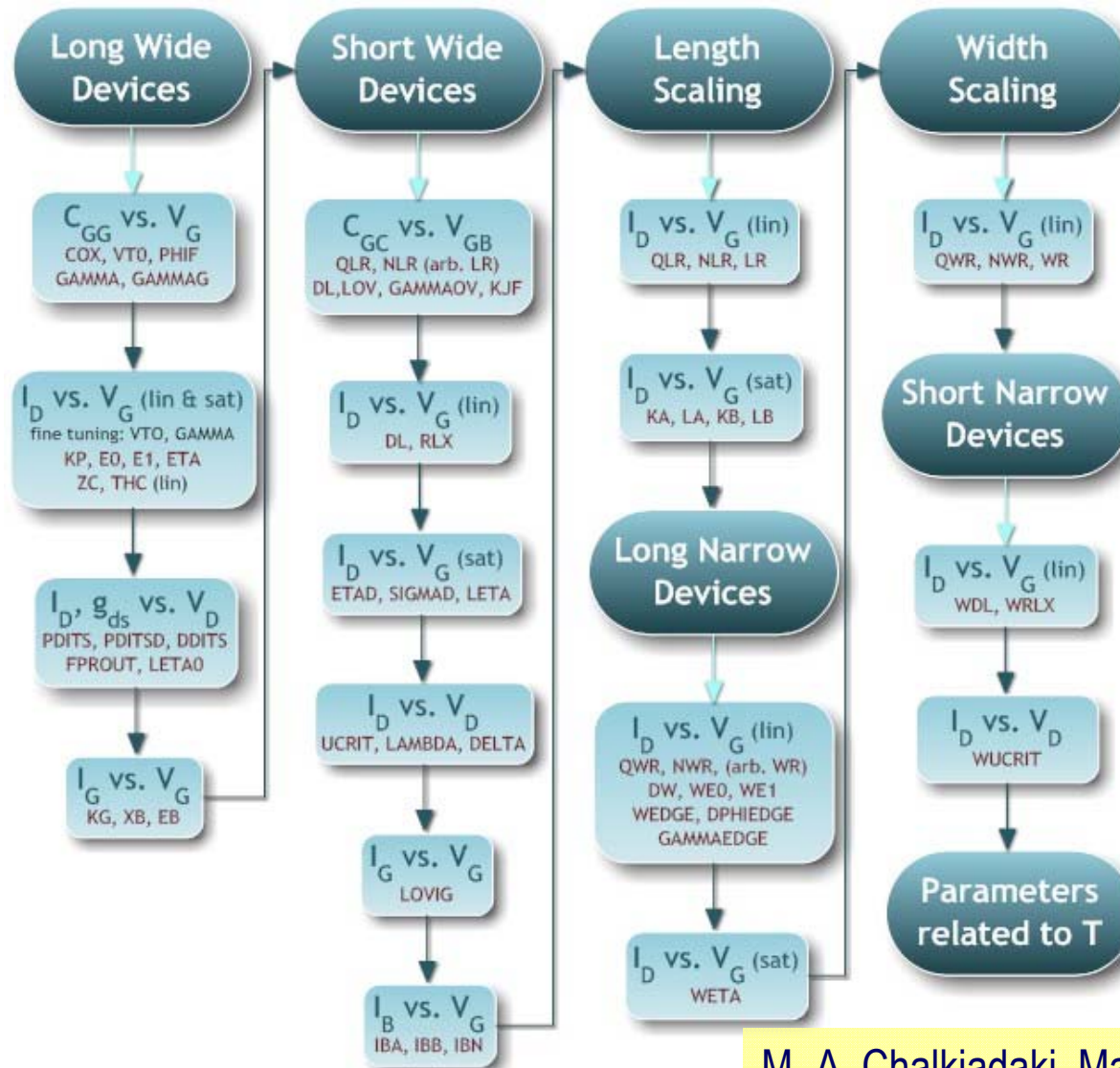
- RSCE, INWE, combined short&narrow-channel effects
- DIBL, charge-sharing
- Halo/pocket implant effects
  - ✓ including @long channel
- Bias-dependent overlap & inner fringing capacitances
- Bias-dependent series resistance
- Geometry & temperature scaling
- Parasitic effects modelling
  - ✓ Layout dependent stress
  - ✓ Edge conduction
  - ✓ Gate tunneling
  - ✓ ....

# EKV3 model basic parameters

PARAMETER	NMOS	PMOS	PARAMETER	NMOS	PMOS	PARAMETER	NMOS	PMOS	PARAMETER	NMOS	PMOS
FLAGS & SETUP PARAMETERS			INVERSE NARROW WIDTH EFFECT			GATE CURRENT			STI STRESS EFFECT		
SIGN	1.0	-1.0	WR	103n	43n	KG	13.9u	24.4u	SAREF	1.423u	1.423u
TNOM	27.0	27.0	QWR	5.5u	306u	XB	5.0	4.98	SBREF	1.423u	1.423u
TG	-1.0	-1.0	NWR	5.1m	-32m	EB	42.0G	29.42G	KVTO	0.0	6.0n
QOFF	0.0	0.0	DRAIN INDUCED BARRIER LOWERING			LOVIG	24n	29.06n	KKP	-38n	32n
XL	0.0	0.0	ETAD	1.19	1.65	IMPACT IONIZATION CURRENT			KGAMMA	0.0	0.0
XW	0.0	0.0	SIGMAD	306m	1.1	IBA	0.0	0.0	KETAD	33n	0.0
SCALE	1.0	1.0	GEOMETRICAL PARAMETERS			IBB	987MEG	445MEG	KUCRIT	-8.8	0.0
OXIDE, SUBSTRATE & GATE DOPING			DL	25.23n	82n	IBN	110m	109m	WIDTH SCALING PARAMETERS		
VTO	91m	-132m	DW	-9n	0.0	EDGE DEVICE			WE0	45n	157n
COX	13.5m	13.1m	DLC	0.0	0.0	DGAMMAEDGE	0.0	0.0	WE1	0.0	0.0
XJ	22n	11.4n	DWC	13.9n	117n	DPHIEDGE	0.0	0.0	WRLX	45n	0.0
PHIF	458m	434m	LL	0.0	0.0	WEDGE	0.0	0.0	WUCRIT	-44n	138n
GAMMA	149m	23.9m	LLN	1.1	1.1	OVERLAP CAPACITANCES			WLAMBDA	0.0	24n
GAMMAG	14.7	5.9	WDL	6f	0.0	LOV	23n	26n	WETAD	0.0	-48n
NO	1.018	1.023	LDW	2.8f	0.0	GAMMAOV	4.1	3.4	WUCEX	0.0	0.0
QUANTUM EFFECTS			DRAIN INDUCED THRESHOLD SHIFT			VFBOV	0.0	0.0	WLR	0.0	0.0
AQMA	18	570m	FPROUT	2.9MEG	9.75MEG	VOV	1.0	1.0	WQLR	0.0	-22n
AQMI	480m	372m	PDITS	57u	14u	FRINGING CAPACITANCE			WNLR	139n	-176n
ETAQM	738m	742m	PDITSL	0.0	0.0	KJF	0.0	0.0	WDPHIEDGE	0.0	0.0
VERTICAL FIELD MOBILITY			PDITSD	190m	780m	CJF	0.0	0.0	LENGTH SCALING PARAMETERS		
KP	1.050m	290.0u	DDITS	9.0	9.0	TEMPERATURE PARAMETERS			LWR	0.0	0.0
E0	130MEG	92MEG	MOBILITY SCALING PARAMETERS			TCV	310u	-530u	LQWR	1.4u	0.0
E1	9.7G	8.1G	KA	380m	0.0	BEX	-1.3	-1.2	LNWR	0.0	-55n
ETA	1.0	1.21	LA	270n	2.7u	TETA	0.0	0.0	LDPHIEDGE	0.0	0.0
ZC	0.9u	0.95u	KB	465m	0.0	UCEX	1.4	3.7	COMBINED SCALING PARAMETERS		
THC	0.0	0.0	LB	19n	165n	TLAMBDA	223m	1.32	WLDPHIEDGE	0.0	0.0
VELOCITY SATURATION & CLM			WKP1	249n	307n	TE0EX	0.0	490m	WLDGAMMAEDGE	0.0	0.0
UCRIT	3.9MEG	16.9MEG	WKP2	605m	-272m	TE1EX	0.0	1.1			
LAMBDA	430m	1.454	WKP3	509m	1.51	IBBT	950u	730u			
DELTA	2.01	1.02	WKP3	509m	1.51	TEMPERATURE & GEOMETRY SCALING			SOURCE-DRAIN SERIES RESISTANCE		
ACLM	838m	827m	LONG & WIDE VTO & GAMMA			TCVL	0.0	-37p	RLX	73u	51u
CHARGE SHARING EFFECT			LVT	1.089	1.076	TCW	82p	31p	RSH	0.0	0.0
NCS	1.6	21	WVT	104u	104u	TCVWL	0.0	0.0	LDIF	0.0	0.0
LETA0	1.2MEG	2.78MEG	AVT	36m	158m	RESISTANCE TEMPERATURE SCALING			HDIF	234n	234n
LETA	1.054	1.54	LGAM	1.098	1.45u	TR	0.0	-4.6m	GATE RESISTANCE		
LETA2	-24n	0.0	WGAM	110u	1.3	TR2	0.0	0.0	GC	1.3	1.3
WETA	0.0	0.0	AGAM	25.8m	-211m				RGSH	52	51
REVERSE SHORT CHANNEL EFFECT			MATCHING PARAMETERS			FLICKER NOISE PARAMETERS			SUBSTRATE RESISTANCE		
LR	67.8n	38.9n	AVTO	0.0	0.0	AF	1.0	1.0	RDSBSH	1.467K	10.9K
QLR	3.4m	8.2m	AGAMMA	0.0	0.0	KF	0.0	0.0	RBWSH	1.2K	1.2K
NLR	78m	7.6	AKP	0.0	0.0	EF	2.0	2.0	RSBWSH	35	56
FLR	1.1	0.0				KGNF	0.0	0.0	RDBWSH	35	56



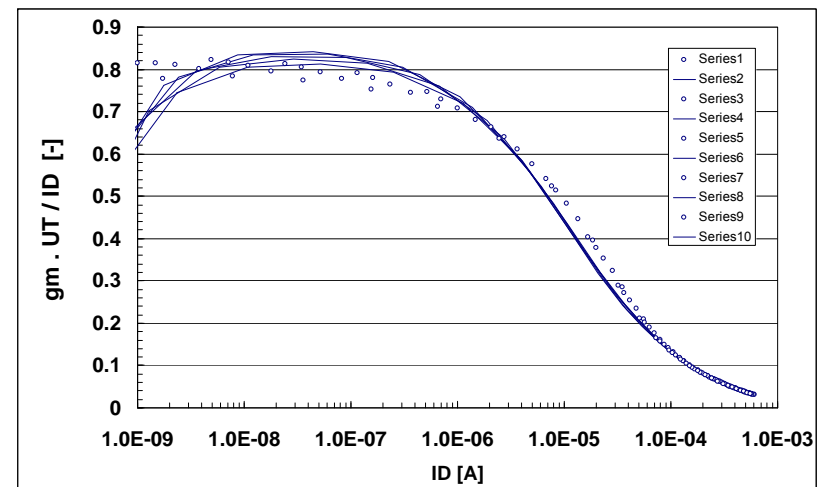
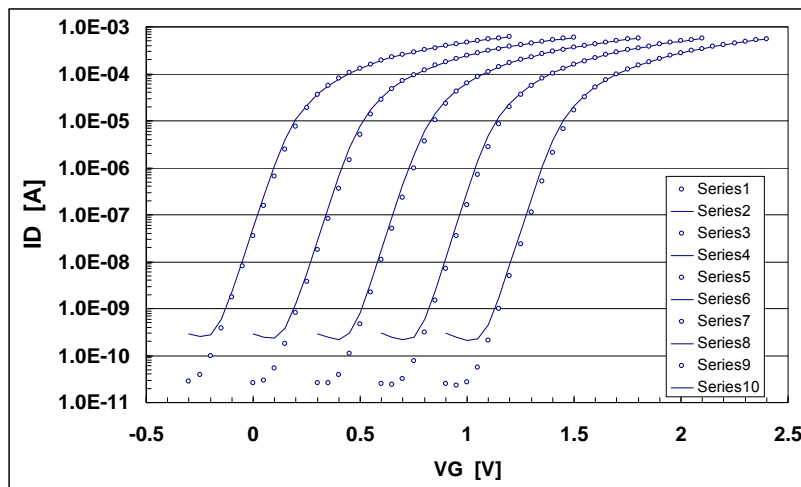
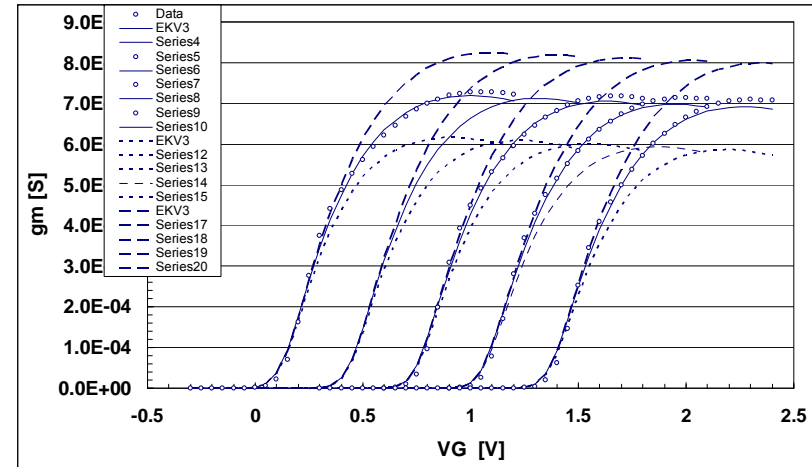
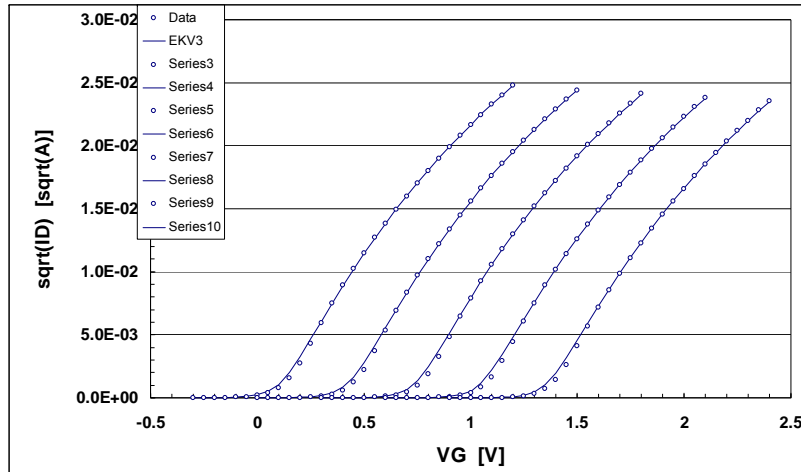
# EKV3 model IV-CV-T parameter extraction



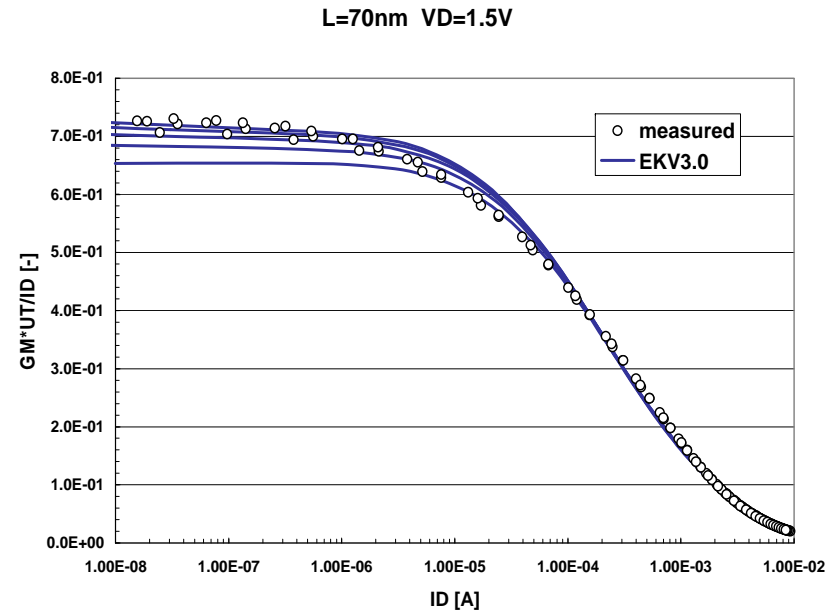
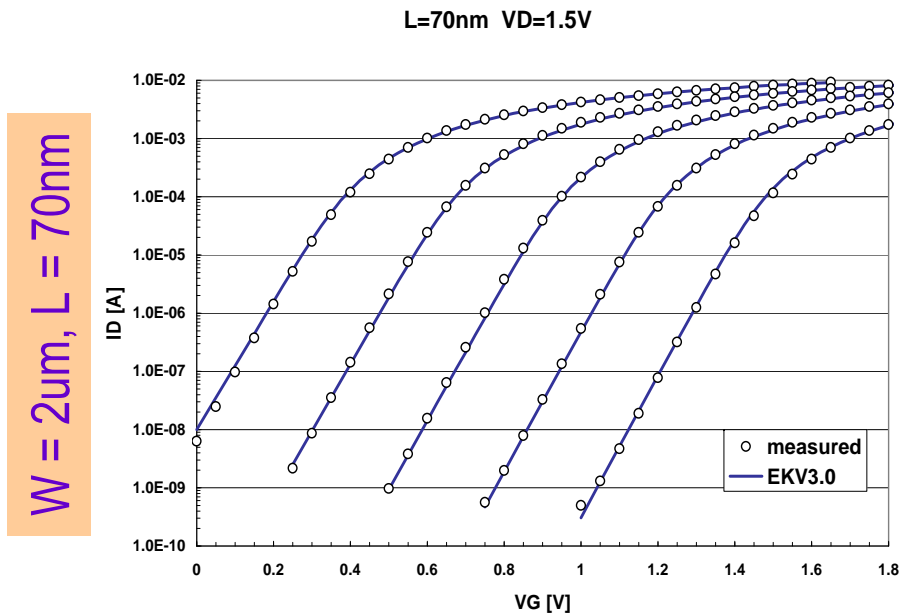
M.-A. Chalkiadaki, Master Thesis, TUC 2011

# EKV3 – long channel

W = 2 $\mu$ m, L = 0.5 $\mu$ m

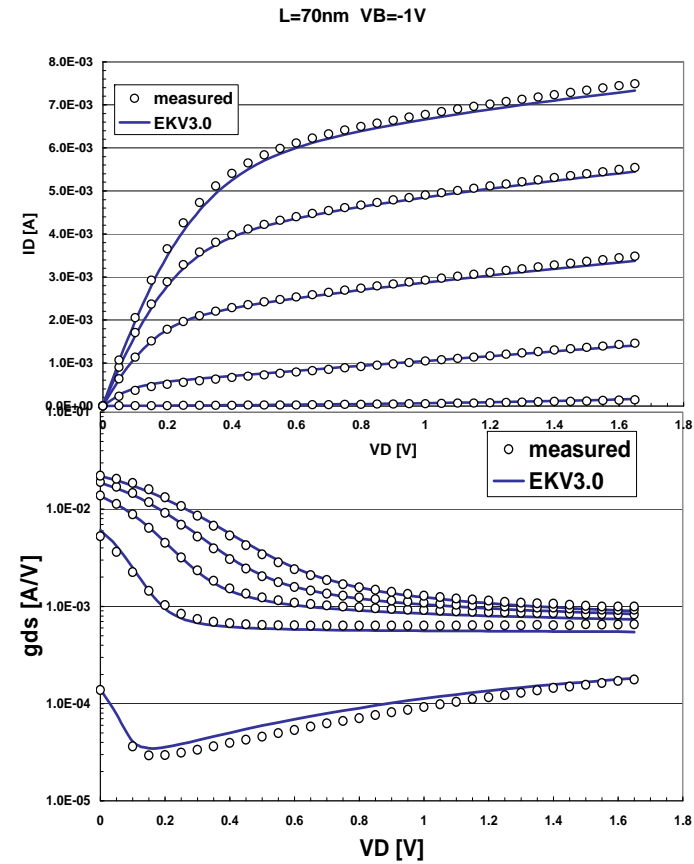
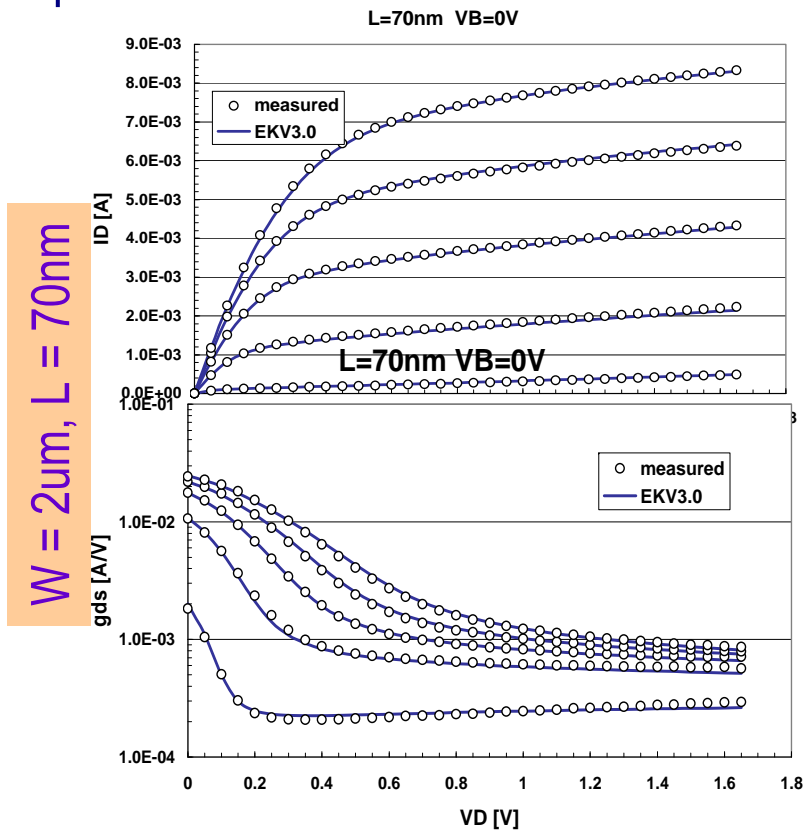


# EKV3 – short-channel



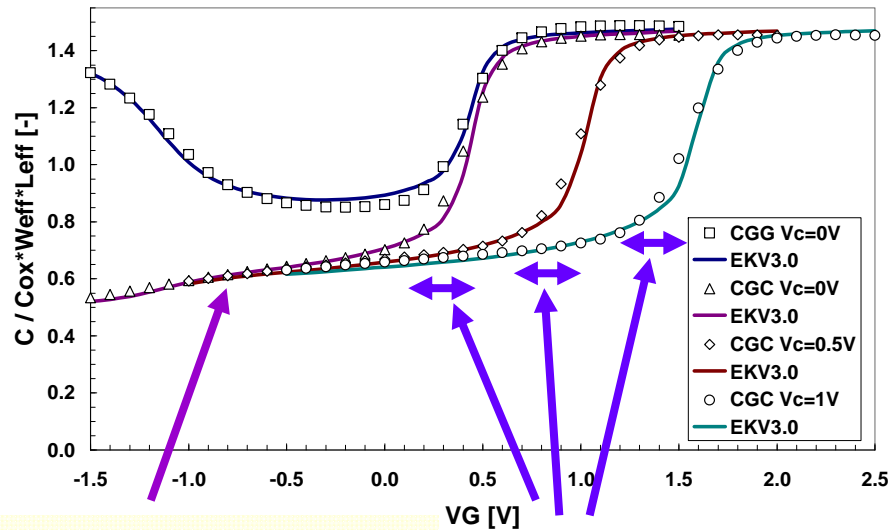
- Correct weak & moderate inversion behavior
  - ✓ Smoothness and correct asymptotic behavior
  - ✓ Correct weak inversion slope and DIBL modelling
- Transconductance-to-current ratio vs. drain current (log. axis)

# EKV3 – short-channel



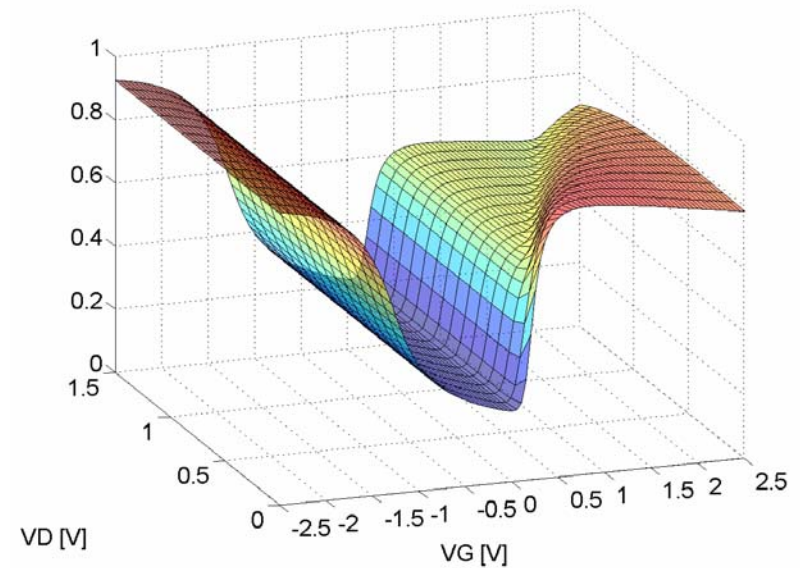
- Illustrates combination of: DIBL, CS, velocity saturation, CLM modelling @ Lgate = 70nm

# EKV3 – CV characteristics of MOSFETs



Overlap & fringing caps.  
(do NOT scale with L)

Moderate Inversion



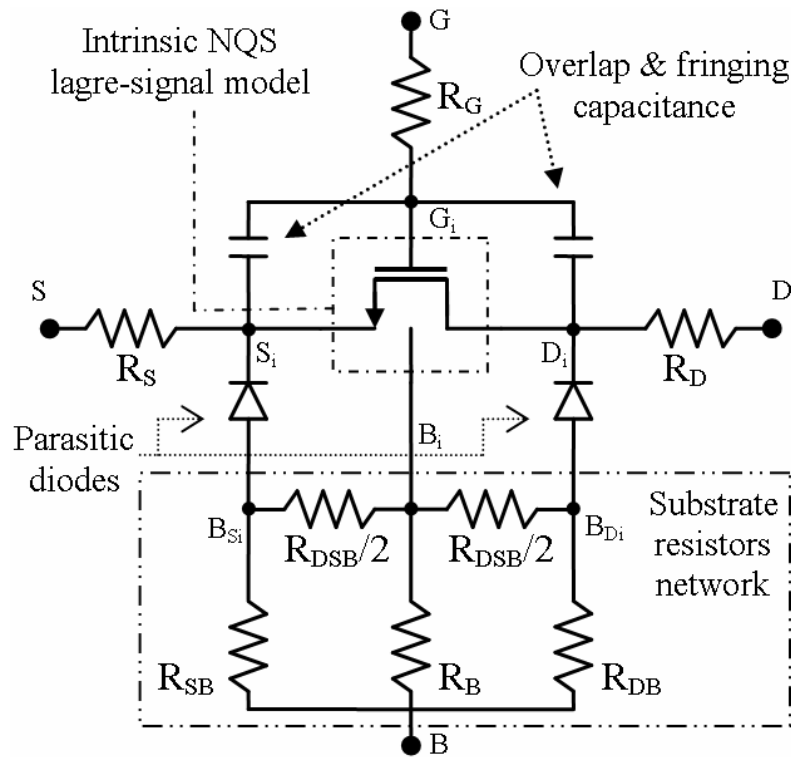
- Moderate inversion in MOSFETs – highly important for analog/RF IC design
- Good trade-off among gain, speed, linearity, noise, matching
- Low-medium saturation voltage, series resistance effect negligible
- Reduced impact of mobility effects (vertical field) and velocity saturation

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# EKV3 scalable model for high frequency

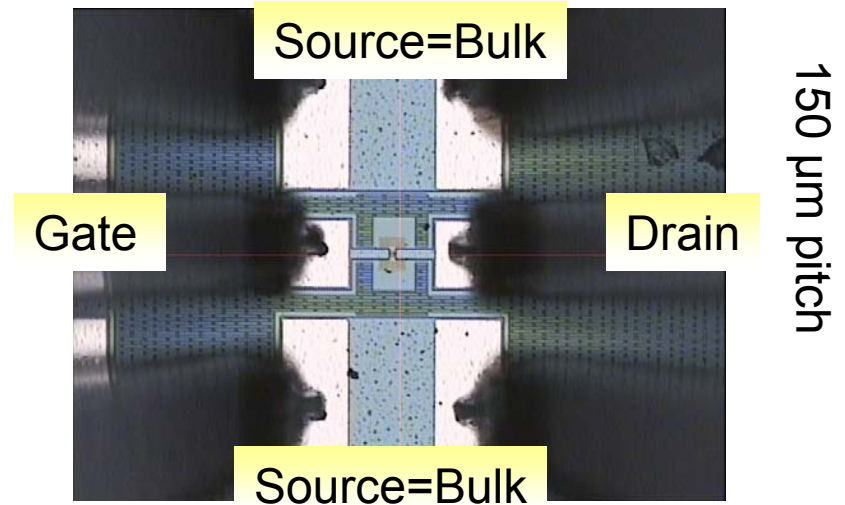
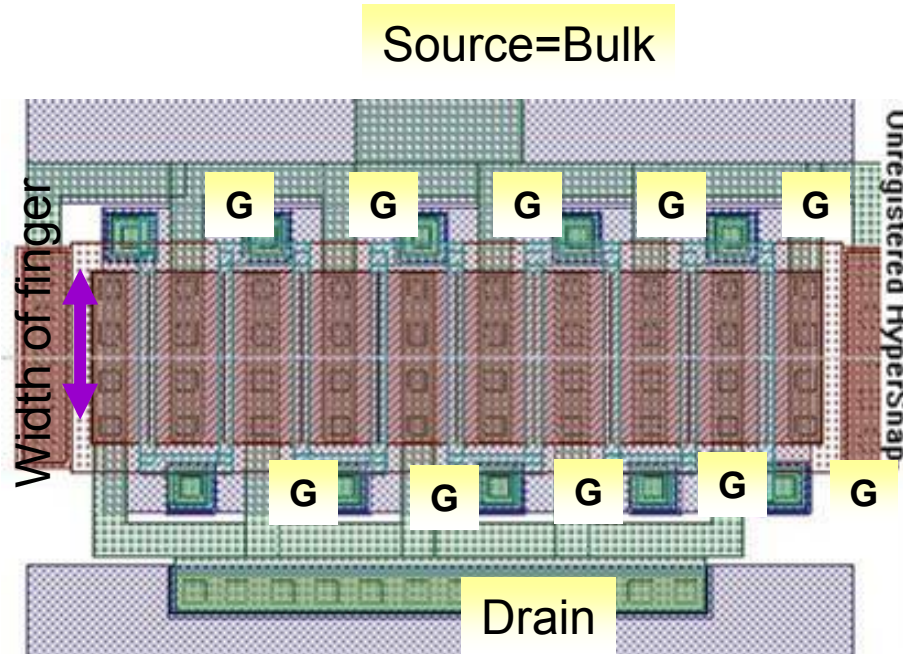


- Non quasi-static model (NQS)
  - ✓ channel segmentation
  - ✓ consistent AC/transient
- Gate- and substrate- parasitics scale with multi-finger layout

$R_G$	$\sim W_f / (L * N_F)$
$R_{SB}, R_{DB}$	$\sim 1 / W_f$
$R_B$	$\sim 1 / W_f$
$R_{DSB}$	$\sim L / (W_f * N_F)$



# Multi-finger RF MOSFETs

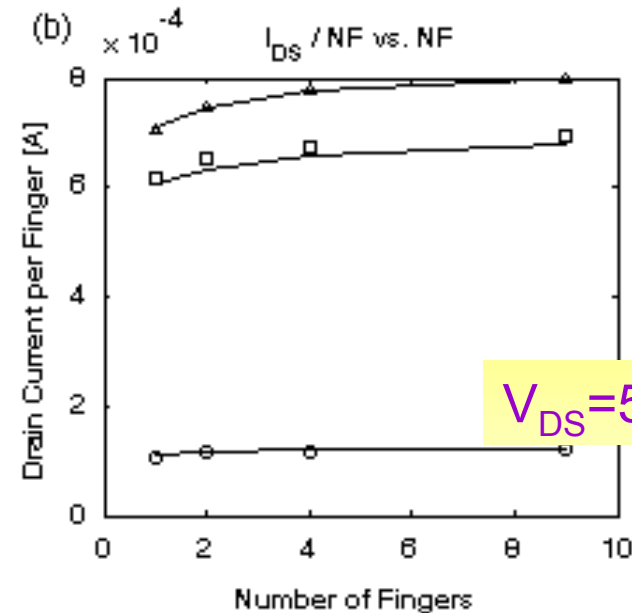
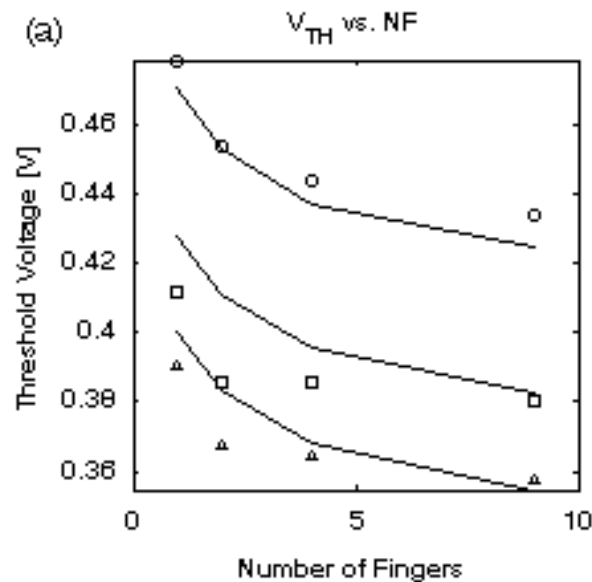


Bazigos e.a., Physica Status Solidi C(5), 2008

- Layout of RF multi-finger MOSFET
  - ✓ Number of fingers –  $N_F$
  - ✓ Finger Width –  $W_f$
  - ✓ Gate Length –  $L$
- Ground-Signal-Ground (GSG) RF Pads
  - ✓ 2 port configuration
- Open-Short de-embedding structures



# STI stress in multi-finger RF MOSFETs



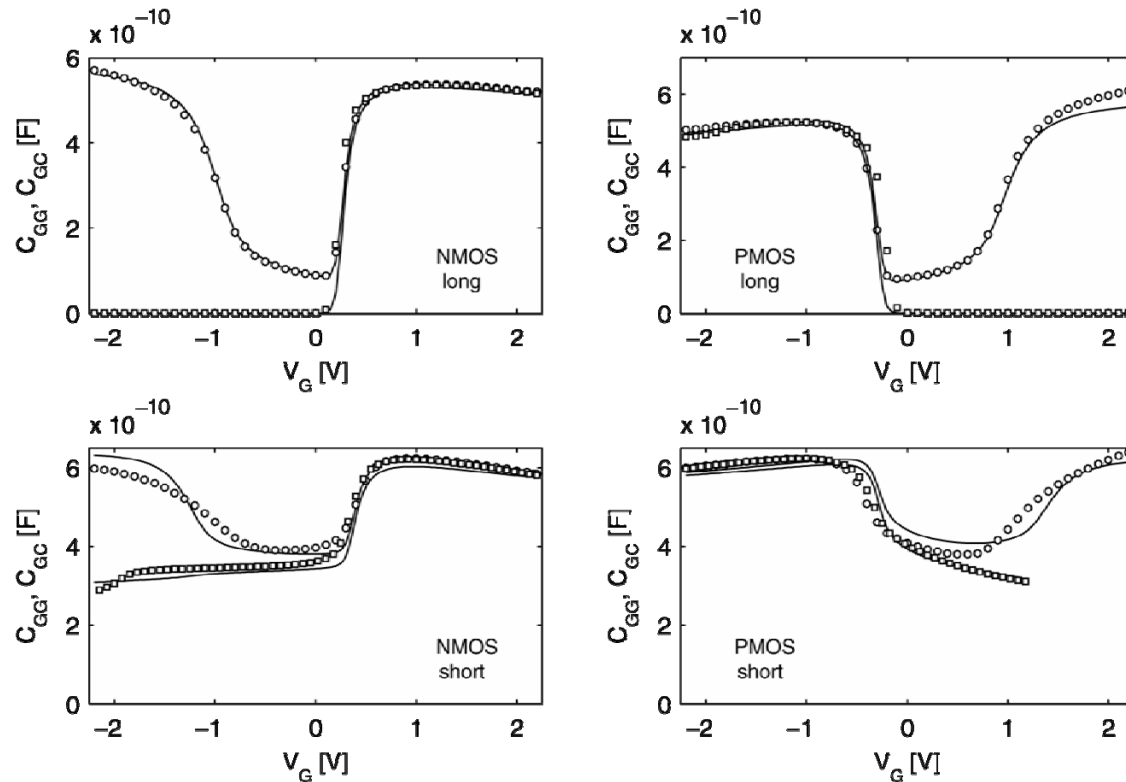
— EKV3  
□ meas.

$V_{DS}=50m, 0.5, 1V$

Bazigos e.a., Physica Status Solidi C(5), 2008

- NMOS,  $L=180nm$ ,  $W_f=2\mu m$
- Layout-dependent stress effects due to shallow-trench isolation (STI)
  - ✓ Threshold voltage dependence  $V_T$  vs.  $N_F$
  - ✓ Max. drain current dependence  $I_D / N_F$  vs.  $N_F$

# CV

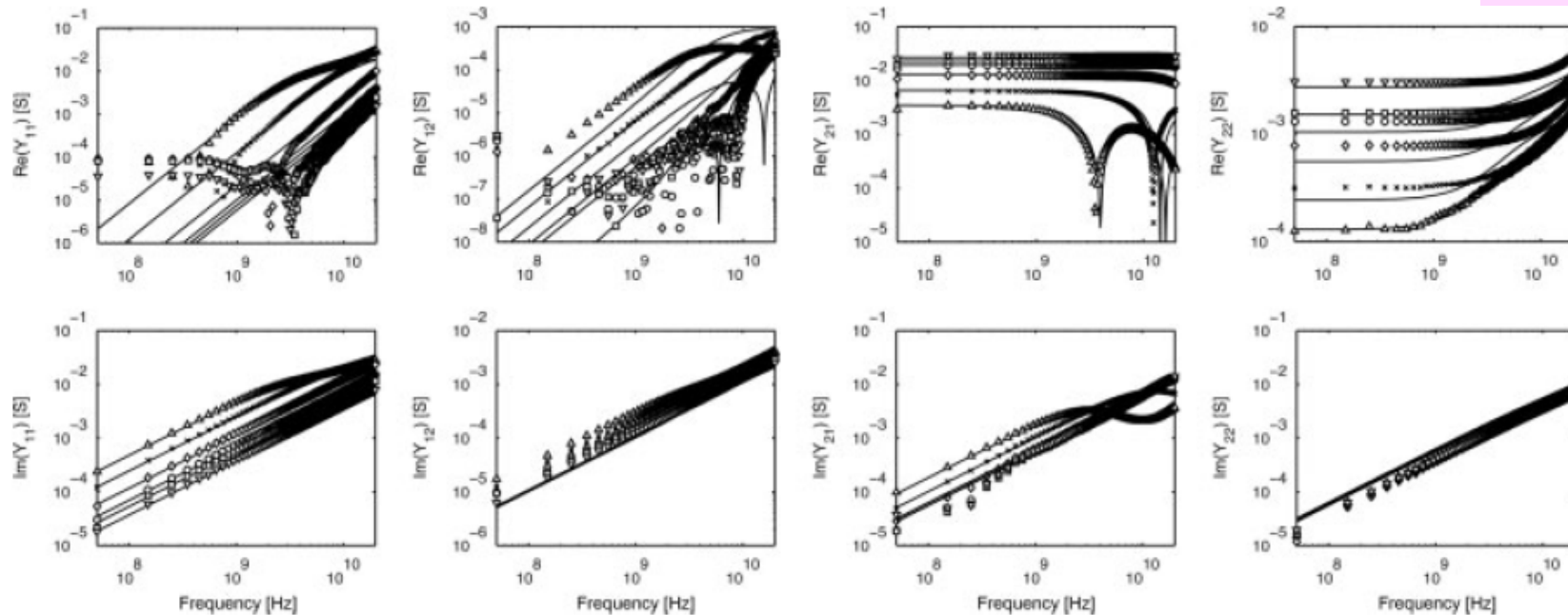


Bucher e.a., RFMiCAE(18), 2008

- Long/short gate and inversion capacitance

# EKV3 RF scalability with L

– EKV3  
□ meas.

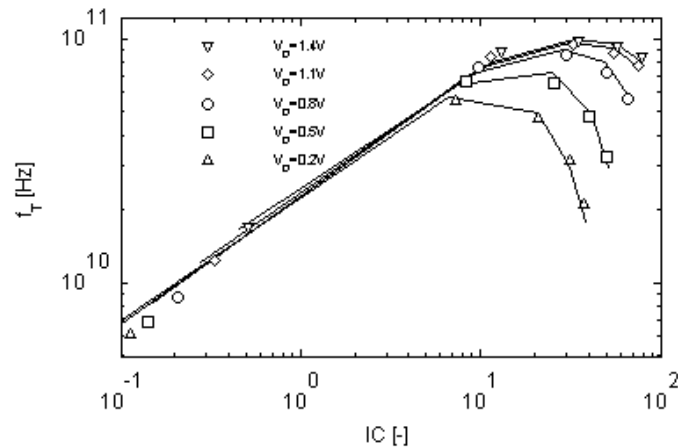


Bucher e.a., RFMiCAE(18), 2008

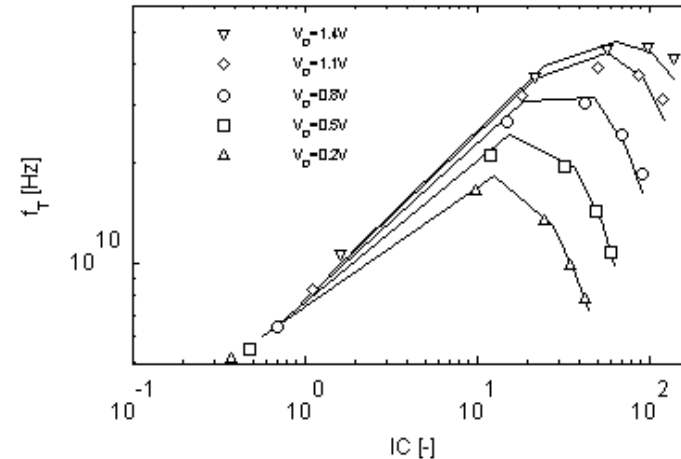
- Y parameter scalability over channel length for NMOS
  - ✓ L=110 nm, 180 nm, 250 nm, 450 nm, 1  $\mu$ m, 2 $\mu$ m
  - ✓ W=5  $\mu$ m, NF=10
  - ✓ VG=0.6V, VD=0.5V

# EKV3 $F_T$ modelling

– EKV3  
□ meas.



NMOS,  $L = 110\text{nm}$

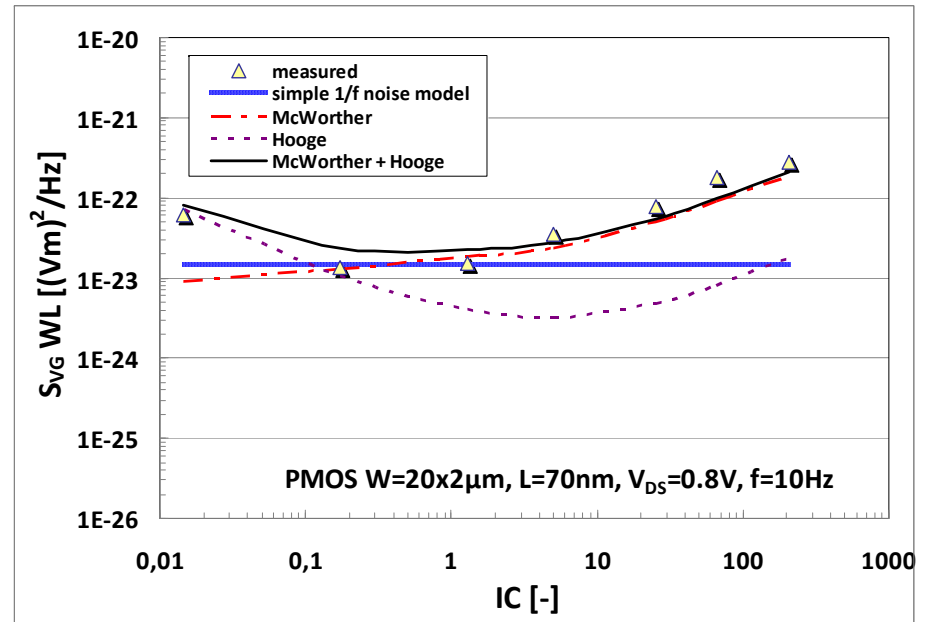
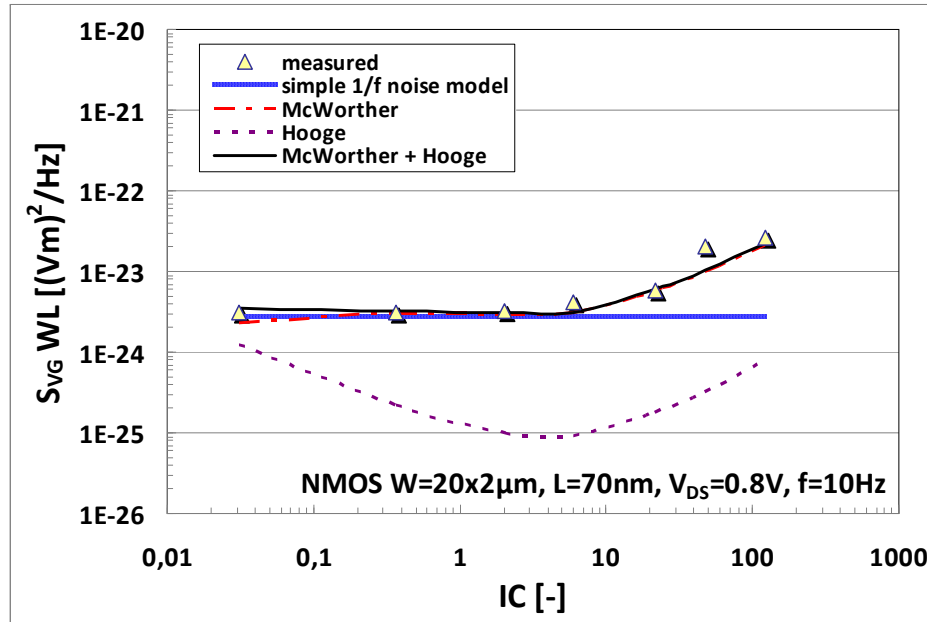


PMOS,  $L = 110\text{nm}$

Bucher e.a., RFMiCAE(18), 2008

- $F_T$  versus  $I_C$  in 110nm CMOS, EKV301.02 model
- Highest  $F_T$  is reached at  $I_C \sim 10\text{-}30$  (!)
- Most probable range for biasing of RF circuits for low noise is:  
 $1 < I_C < 20$  (depending on technology and application)

# Low frequency noise with EKV3.1



Mavredakis e.a., WCM-NanoTech, 2010

- Bias dependence of low frequency noise covered (EKV3.1)
- Combines carrier number and mobility fluctuations
- Increase in noise in strong inversion
- Increase in noise (referred to gate) may also be observed in weak inversion

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# Outline

- Motivation – the need for moderate inversion design
- Evolution of CMOS device performance – from planar bulk to Double-gate and FinFET
- EKV3 charge-based compact model
- EKV3 high-frequency model
- Conclusions

# Conclusions

- Moderate inversion design even at RF (scaling!)
- Future (today!) DG and FinFET technologies give:
  - better short-channel behaviour, higher intrinsic gain. FT may be degraded @same channel length
- EKV3: analog/RF IC design-oriented, charge-based, compact model
  - ✓ Native implementations in: ELDO (Mentor Graphics), Smash (Dolphin), Spectre (Cadence), Smartspice (Silvaco).
  - ✓ Parameter extraction support (GMC Suisse & AdMOS)
  - ✓ Model covers all RF aspects from DC to RF (small/large signal including NQS) and Noise.
  - ✓ Extended RF validations in 180nm, 110nm, 90nm CMOS.
  - ✓ Fully scalable with L, W, NF, bias, f, technology.
  - ✓ Simple model structure & parameter extraction.
- EKV3.1 new model release in 1<sup>st</sup> quarter 2012.

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